

Abstract**Vacuum chamber arrangement**

5 According to various embodiments, a vacuum chamber arrangement (100) can have the following: a vacuum chamber (102), which has a first supply passage (102v); a substrate holding arrangement (104) having a substrate holder (110) for holding and positioning at least one substrate, a vacuumtight
10 supply housing (108) for supplying the substrate holder (110) with at least one supply medium, wherein the supply housing (108) has a second supply passage (108v); a bearing arrangement (106), by means of which the substrate holding arrangement (104) is supported movably within the vacuum
15 chamber (102); and a supply hose (112), which links the first supply passage (102v) to the second supply passage (108v).

Figure 1A